

00684.002700.1

PATENT APPLICATION

#14
10-31-02
JLR

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Yasuyuki UNNO

Application No.: 09/523,735

Filed: March 13, 2000

For: PROJECTION OPTICAL SYSTEM AND
PROJECTION EXPOSURE APPARATUS
HAVING THE SAME

)
: Examiner: P. Kim

)
: Group Art Unit: 2851

)
: October 28, 2002

Commissioner for Patents
Washington, D.C. 20231

Amend
Drawings
Examiner
Group 2851
Oct 23 2002
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SUPPLEMENTAL REQUEST FOR APPROVAL OF DRAWING CHANGES

Sir:

Further to the Request for Approval to Amend the Drawings filed on October 30, 2000, Applicant requests that the Examiner approve the changes to Figures 3 and 29, as shown in red on the attached sketches, enclosed in duplicate.

In Figure 3, on the axis of the abscissa, change “P(r,Q)” to -- P(r,θ) --, as shown.

In Figure 29, change reference numeral “4” to -- 104 --, as shown.

Favorable consideration is requested.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010 All correspondence should continue to be directed to our address given below.

Respectfully submitted,

Steven E. Warner
Attorney for Applicant
Steven E. Warner
Registration No. 33,326

FITZPATRICK, CELLA, HARPER & SCINTO
30 Rockefeller Plaza
New York, New York 10112-3801
Facsimile: (212) 218-2200
SEW/eab

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